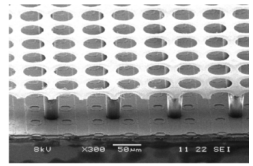


Status of the European Pixel Modules

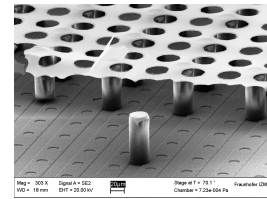
J. Kaminski
for
U. Bonn, NIKHEF, SACLAY



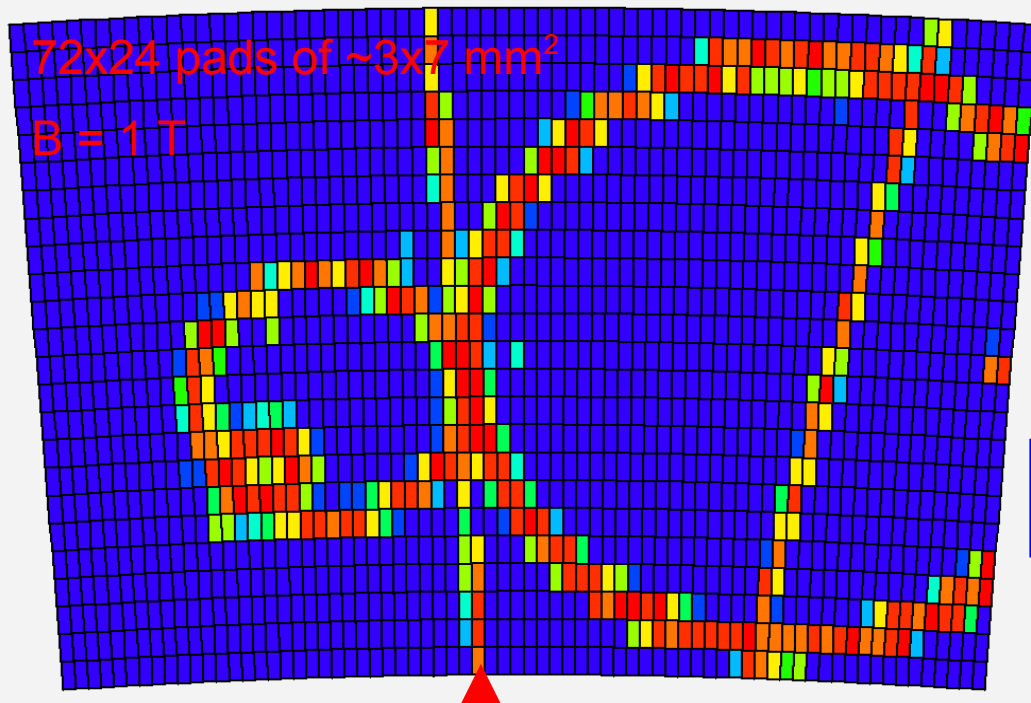
LCTPC Collaboration Meeting, DESY
26th-27th March 2012



Why highly pixelized modules?

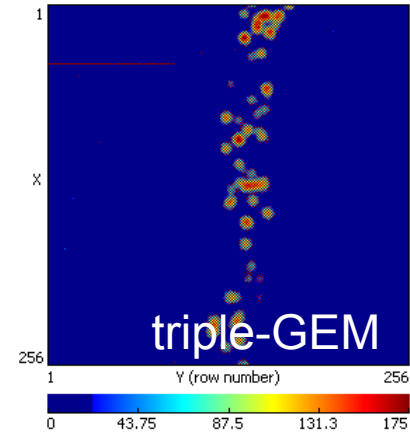


Standard MPGDs use pads of the size $O(\text{mm}^2)$ or long strips with a pitch of $O(100\text{-}200 \mu\text{m})$. This does not fully exploit the resolution of MPGDs.

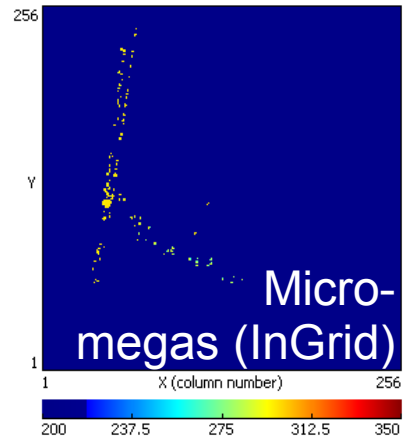


Need smaller pads
 $O(50\text{-}100 \mu\text{m})$
 \Rightarrow Timepix

Timepix



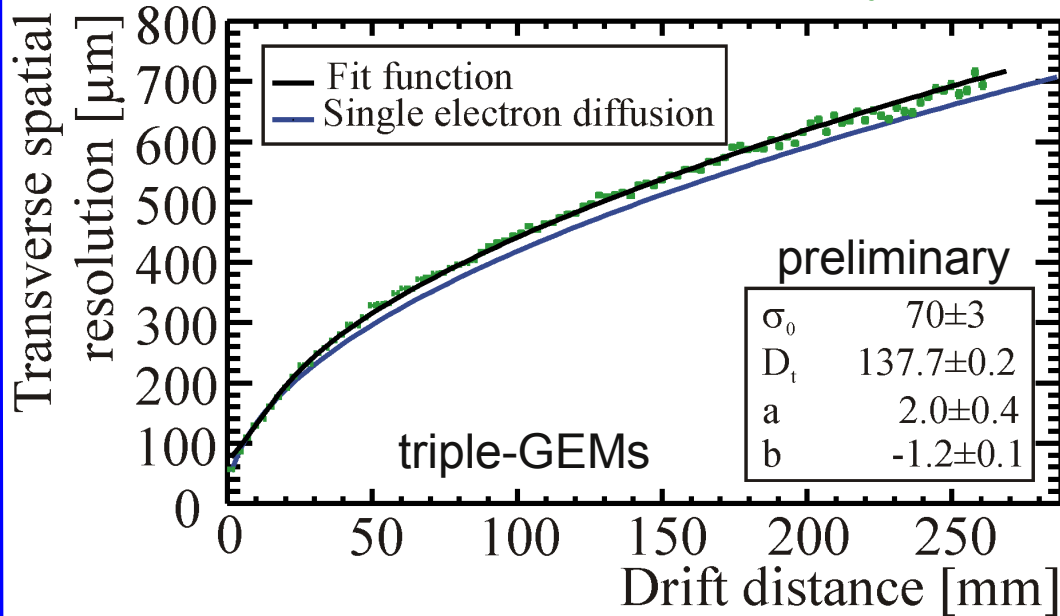
triple-GEM



Micro-megas (InGrid)

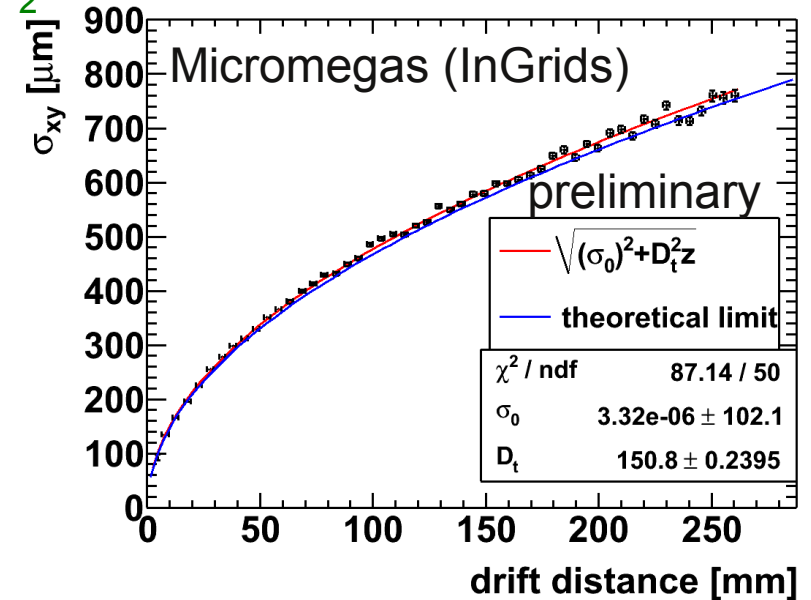
Excellent performance in small prototype detectors

Cosmic rays, He:CO₂ 70:30, B = 0 T



Fit function:

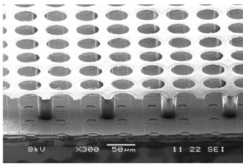
$$\sigma = \sqrt{\sigma_0^2 + D_t^2 z / (1 + a e^{bz})}$$



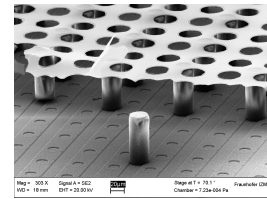
Theoretical limit:

Single electron diffusion

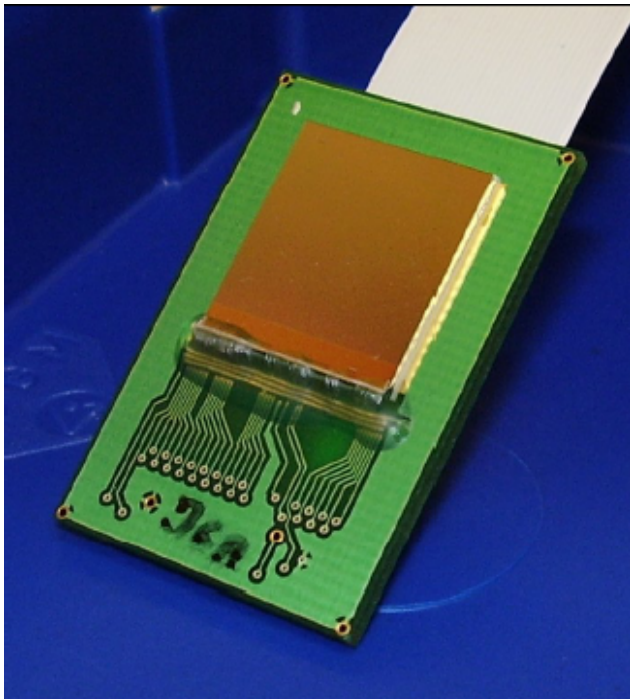
$$\sigma = D_t \sqrt{z}$$



Timepix chip



Bare CMOS chip is placed below the gas amplification stage (GEM or Micromegas), bump bond pads act as charge collection pads.



Timepix chip derived from MediPix-2

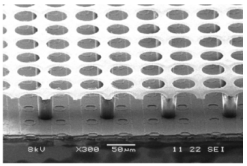
256 × 256 pixels

Pixel size: 55 × 55 μm^2

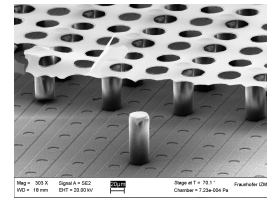
Chip dimension: 1.4 × 1.4 cm^2

Each pixel can be set to one of these modes:

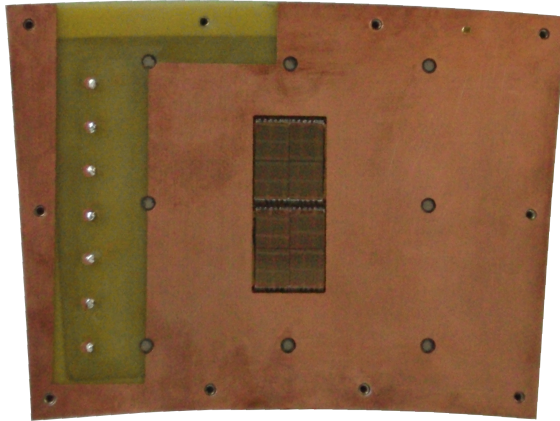
- Hit counting
- TOT = time over threshold
gives integrated charge
- Time between hit and shutter end



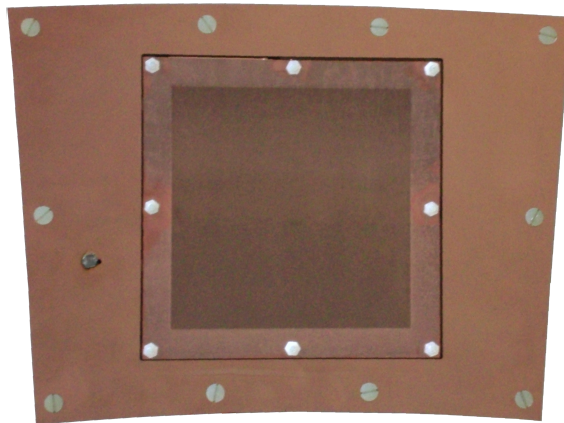
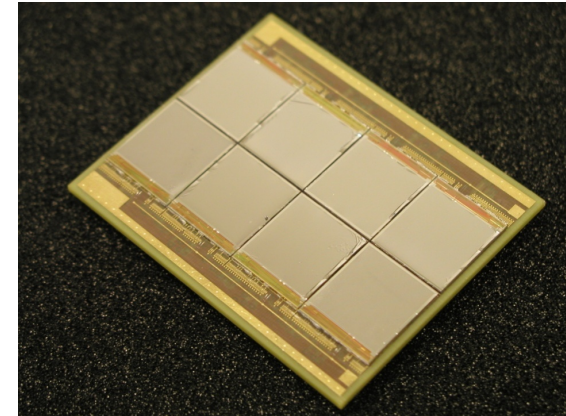
Past LP-modules



LP-modules were built with the two different gas amplification stages

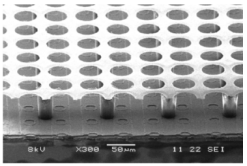


Triple-GEM U Bonn/Freiburg
3 standard CERN-GEMs
2 NIKHEF-Quadboards read out by MUROS
synchronized with EUDAQ/TLU

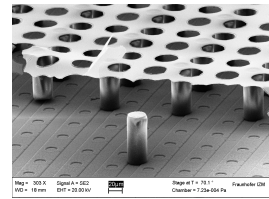


InGrid SACLAY/NIKHEF
8 InGrids on a custom designed board Octopuce read out by one MUROS

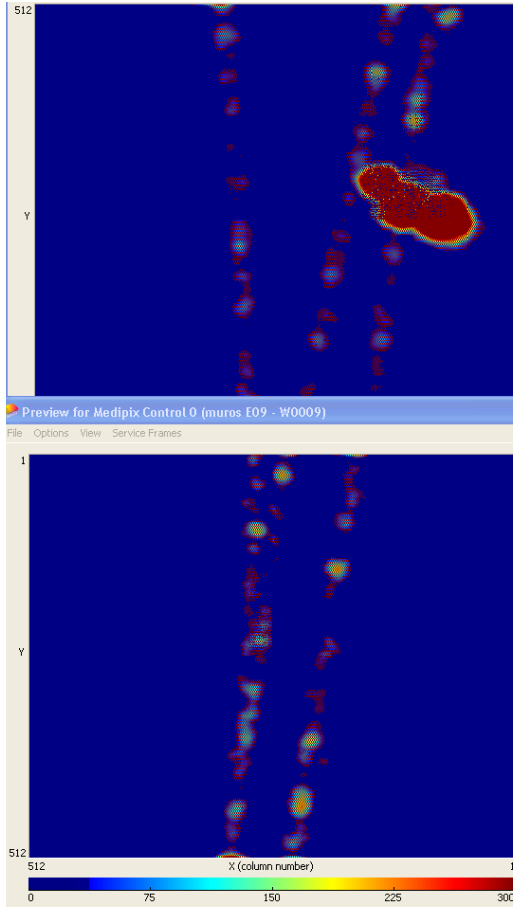




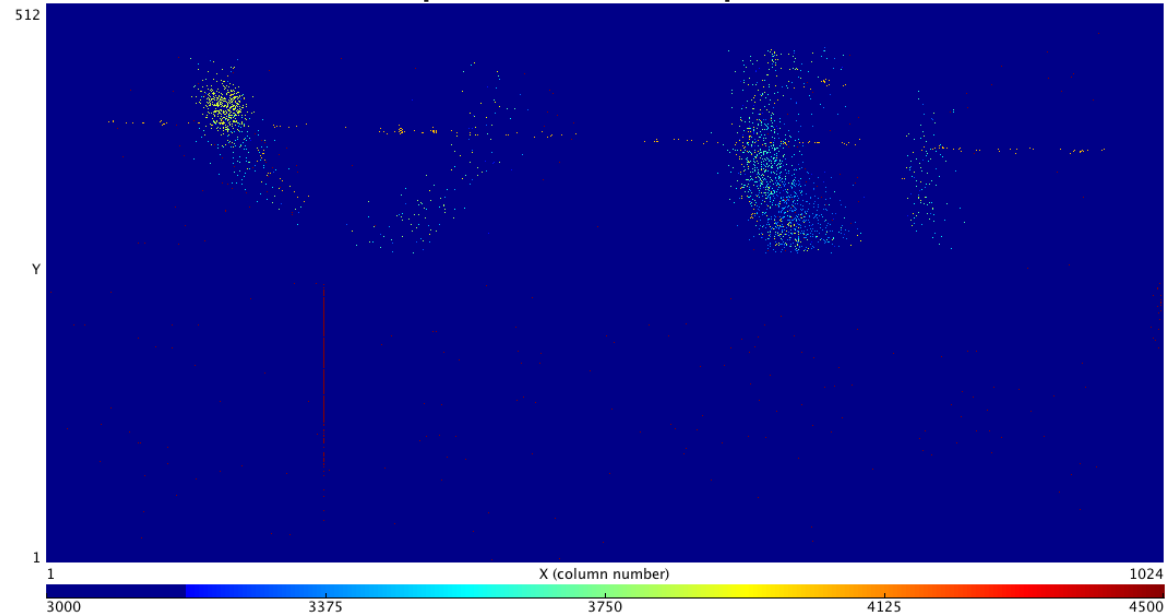
Example event



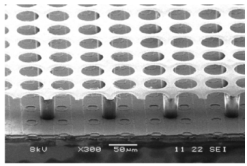
tGEM: T2K, $d = 6$ cm, $B = 1$ T



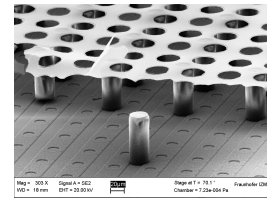
Octopuce – 8 Timepix + InGrids



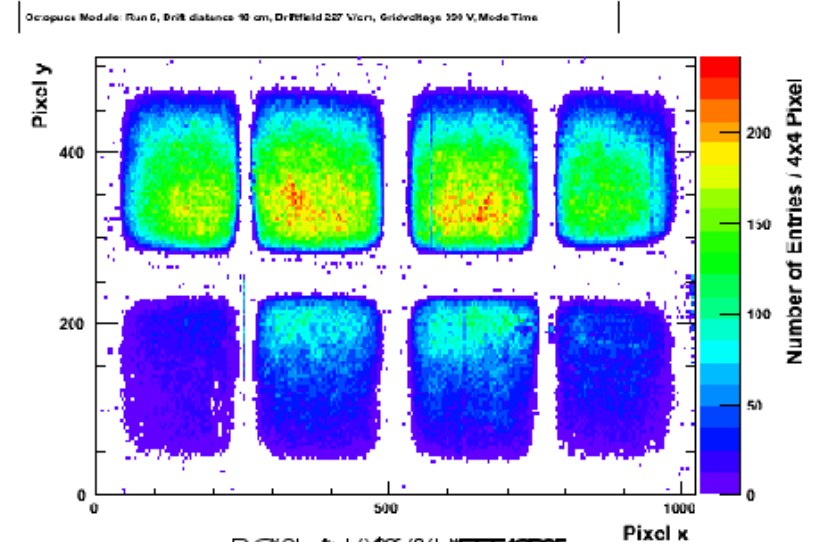
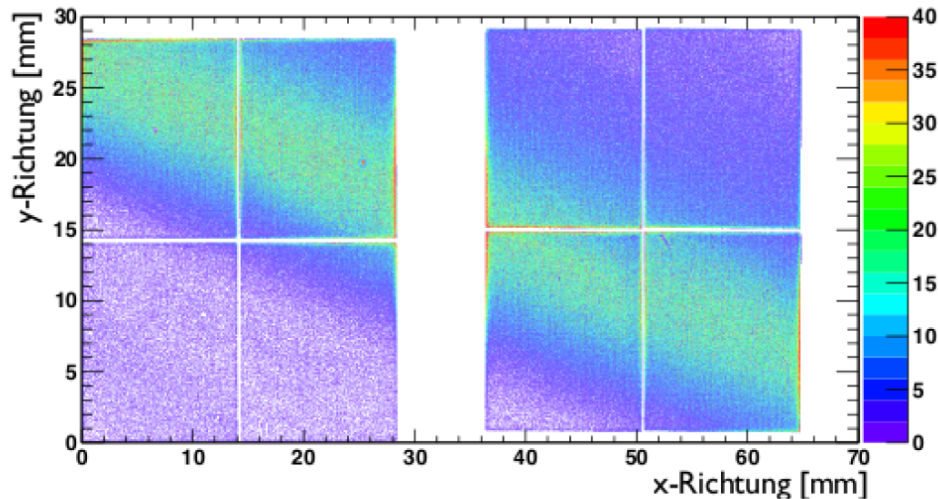
$\text{He}/i\text{C}_4\text{H}_{10}$ 80/20 $V_{\text{grid}} = -400$ V $B = 1$ T



Results from past modules



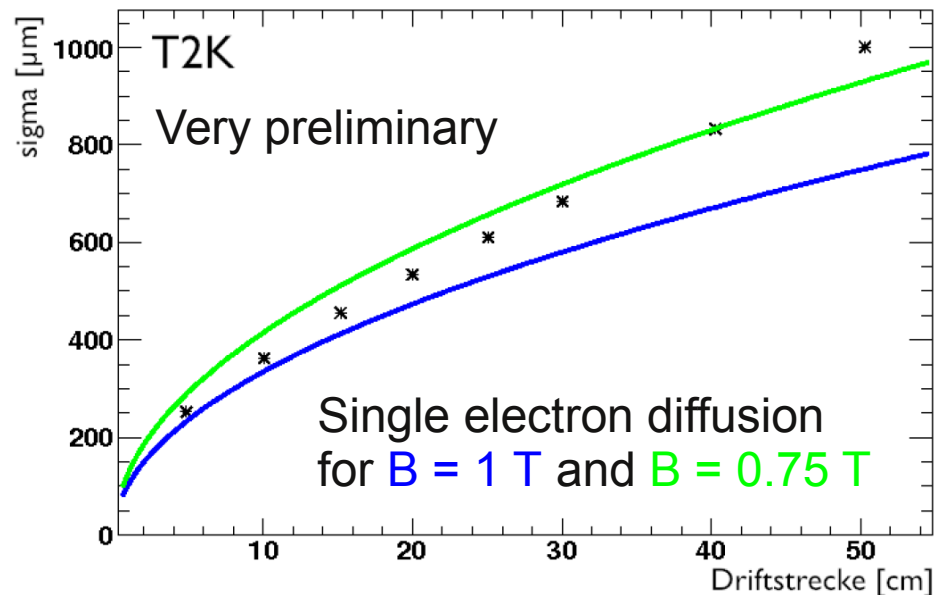
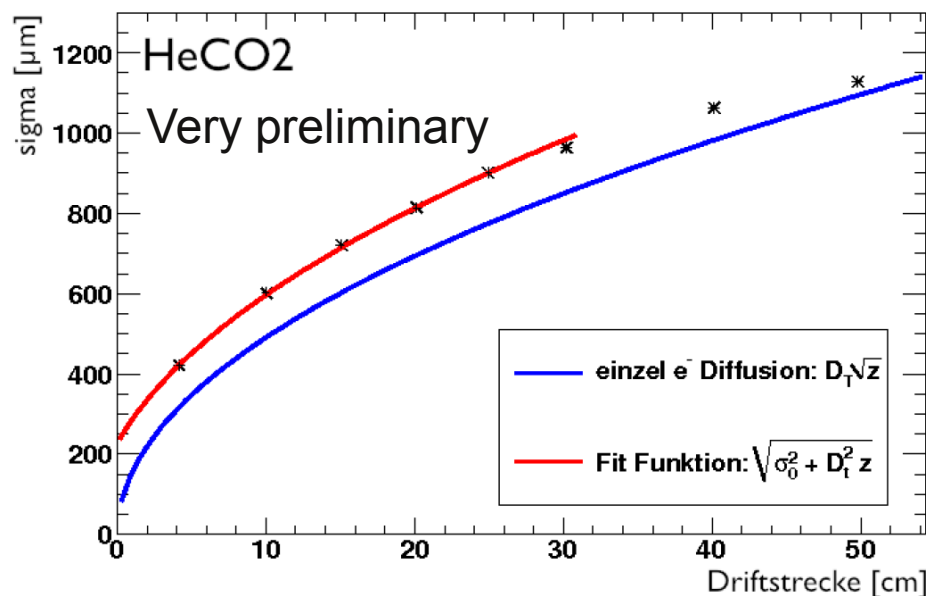
For both modules the results were not as good as expected:
Triple-GEM module suffered from inhomogeneous B-fields
InGrid module suffered from E-field inhomogeneities between
Grids and due to bonding wires.

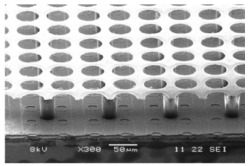


Improved modules are being designed.

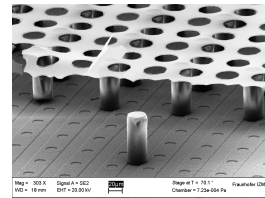
Some more results for tGEM

Data was taken before PCMAG was placed on a movable stage.
=> field inhomogeneities were more prominent as was observed with GEM and MM modules

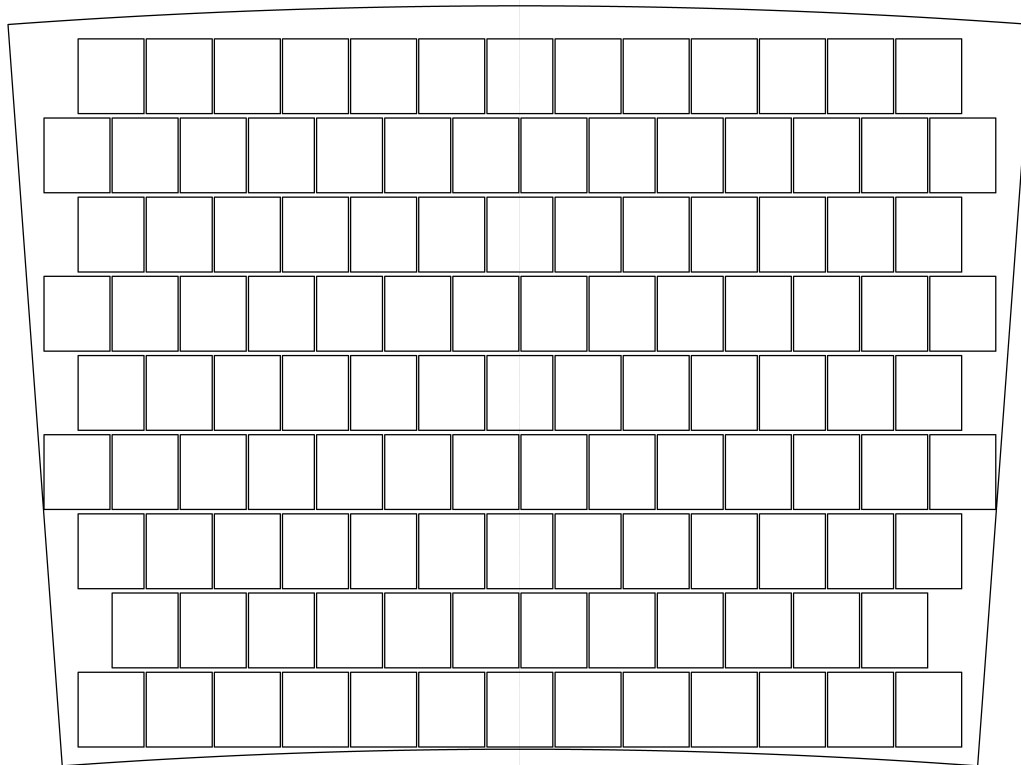




Road map towards a full module



A fully equipped module could hold up to 120 Timepix chips.
This raises several issues, which have to be solved:



Optimistic sketch

Production of InGrids:

current production technique
single/9 InGrids at the Twente,
production takes about a week
producing 120 is unrealistic

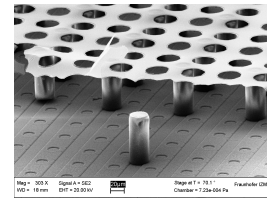
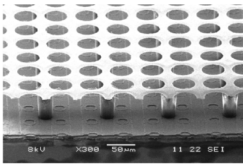
Cooling

each TP produces ~ 1 W
→ have to cool ~ 120 W

Readout

current readout (MUROS) is
not scalable nor in production

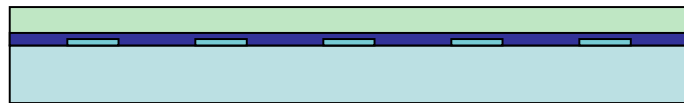
Production of new InGrids (I)



A new wafer-based production process is being established at IZM, Berlin



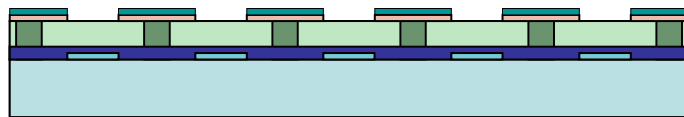
1. Formation of Si_xN_y protection layer (done at Twente)



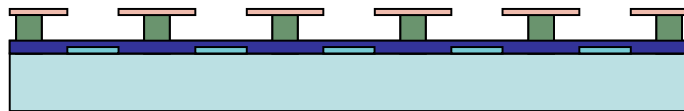
2. Deposition of SU-8



3. Pillars-like structure formation



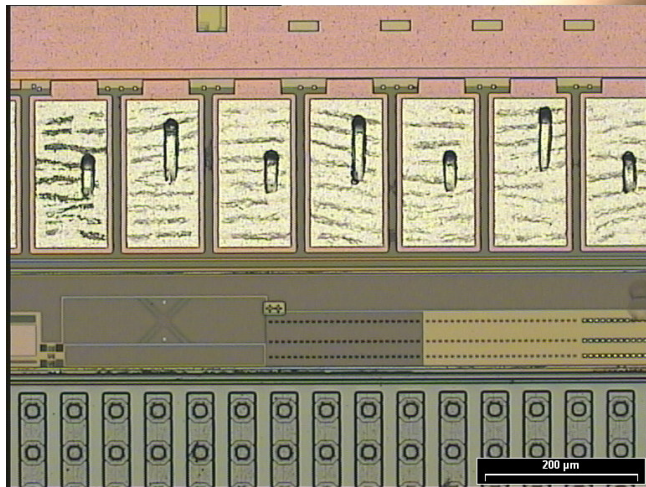
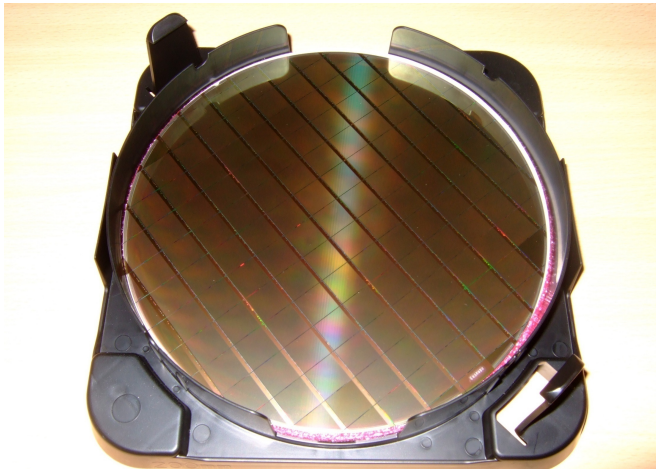
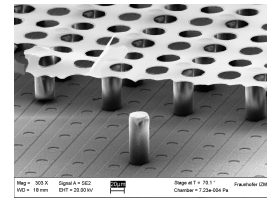
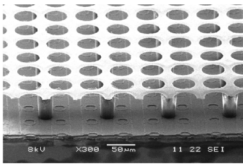
4. Formation of Al grid
4b dicing of wafer



5. Development of SU-8

Process not quite straight forward: protection layer and SU-8 development difficult

Production of new InGrids (II)



Protection layer should cover only active area,
not wire bond pads.

=> bond pads have to be protected

Use polyimide layer

Spinning

Baking

Exposition

Development

Silicon nitride deposition

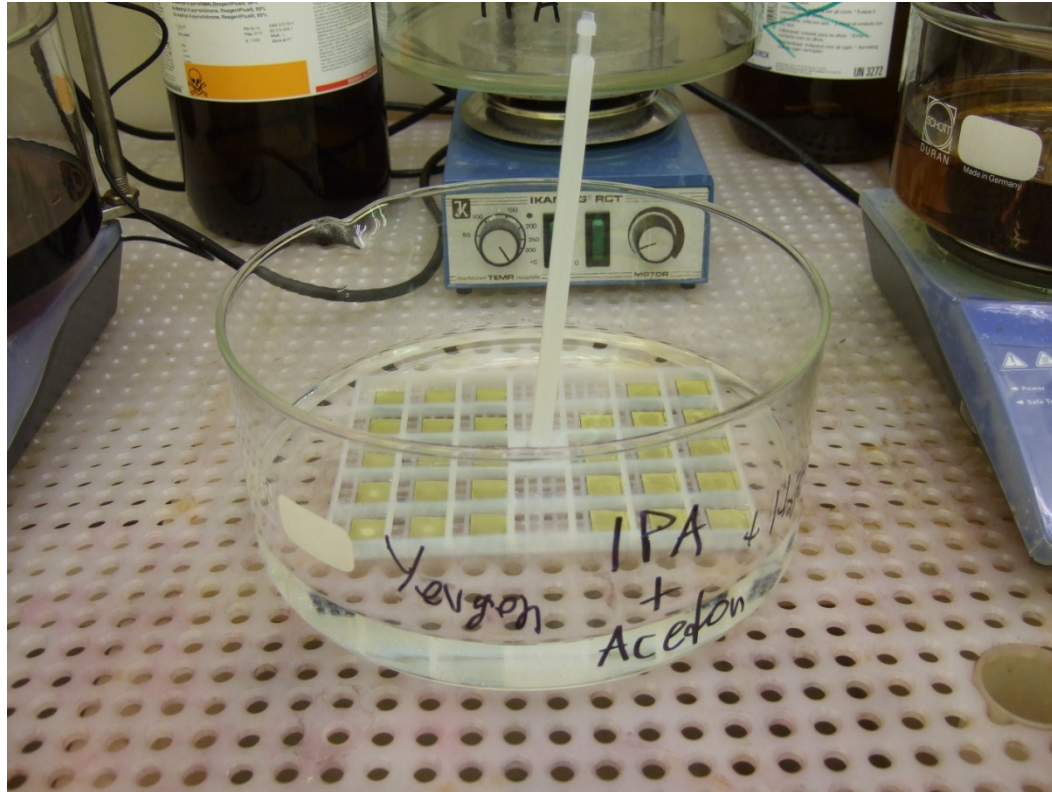
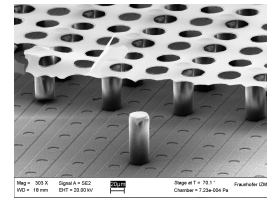
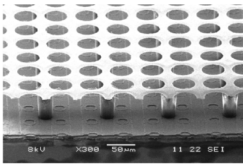
Chemical activation of polyimide

Stripping

Advantage: Silicon technology compatible,
perfect alignment, no residuals

Disadvantage: temperature sensitive process,
time consuming process, mechanical
scratching of bonding pads

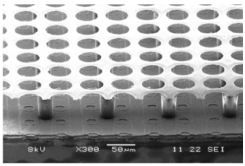
Production of new InGrids (III)



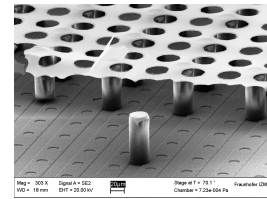
Development of SU-8

- 1) Acetone
- 2) Acetone:IPA:H₂O (1:1:2)
- 3) Acetone:IPA:H₂O (1:1:1)
- 4) Acetone:IPA (1:1)
- 5) Microstrip 6001
- 6) H₂O
- 7) IPA
- 8) Acetone
- 9) Drying in the air

Has to be done after dicing to ensure the stability of the grid during dicing



Status of production

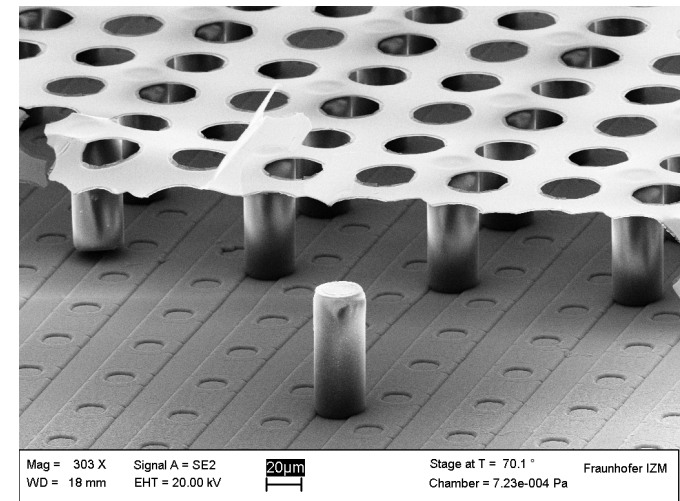
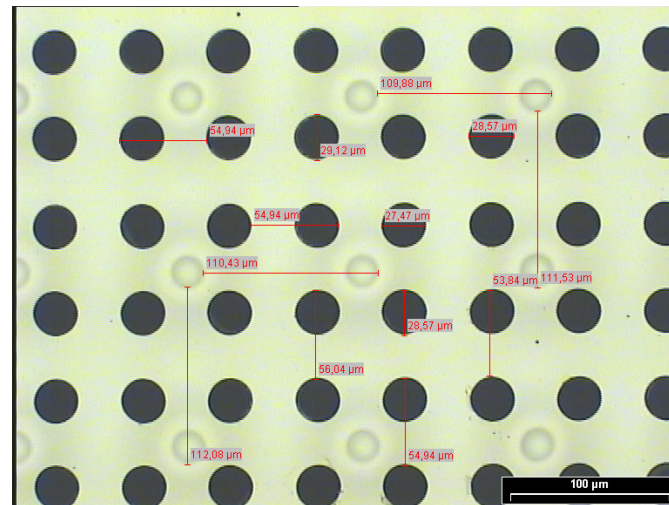
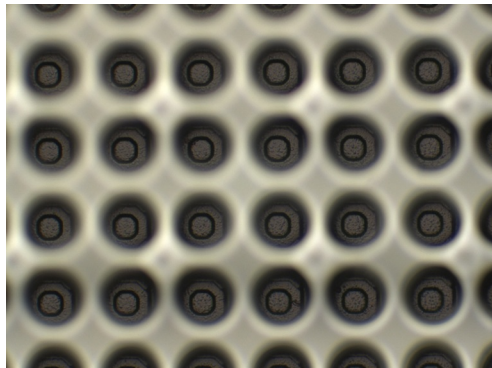


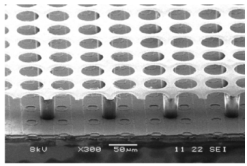
First wafer (fall 2011) was a test run

→ several problems with protection layer and SU-8 development

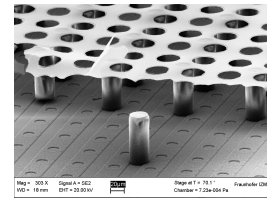
Second wafer (December 2011) yielded >64 good InGrids delivered to Bonn, NIKHEF, Saclay

Grids look very good, are robust and of high quality





First results with new InGrids



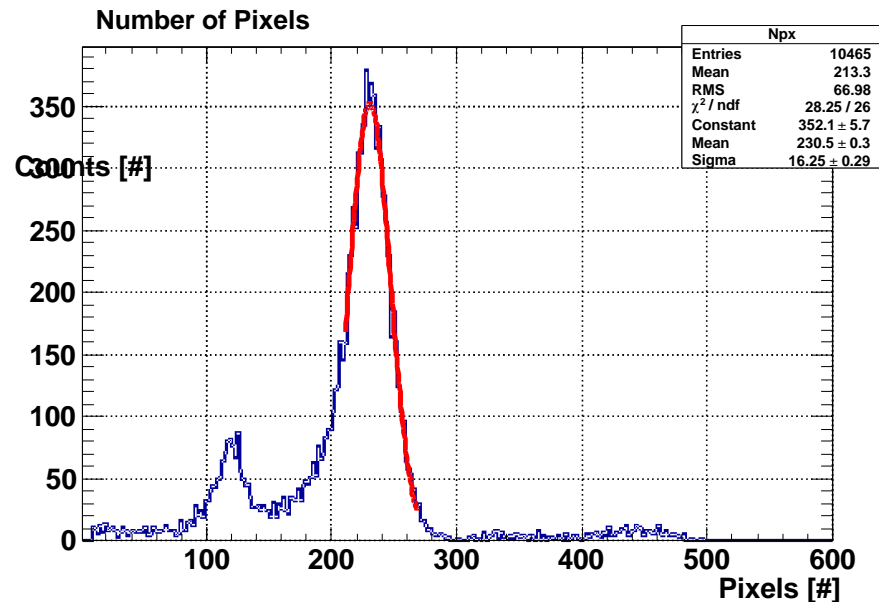
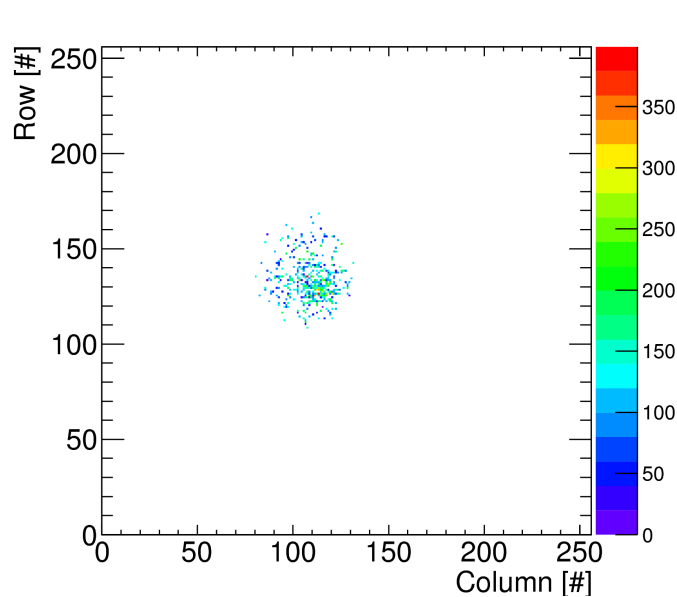
Drift field: 200 V/cm

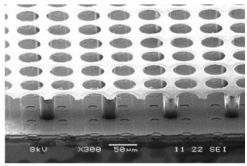
Grid voltage: 350 V

Gas mixture:
Ar:iButane 95:5

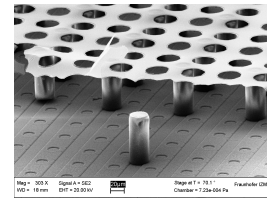
Source ^{55}Fe

Energy resolution σ_E/E :
7.0 % (pixel spectrum)





Some more improvements



... are needed for the protection layer

Twente-InGrids: survive months/years of operation

New IZM-InGrids die after 2 weeks (or less)

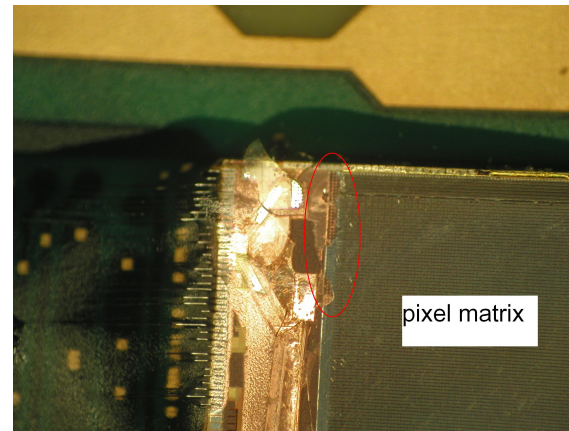
Investigation has started

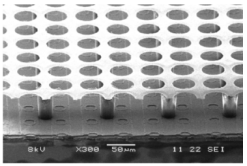
(google spreadsheet to collect information from all institutes, detailed optical and mechanical inspection of broken chips, ...)

a few ideas have been voiced

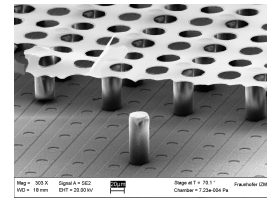
Timepix wafers (chips) control

Chip ID	Type (initial probing)	Final postprocessing	Final control	Location	Responsible person	Operational experience					
Z	Date	Comments	Comments	Date	Location	Date	Name	Purpose	Commissioning (Date)	Maximum HV reached (Gas - default: Ar/Butane 95%)	Grid leakage current (nA)
67	C		bad grid	14.12.2011	Saclay						
67	B										
67	C		bad grid								
67	A			14.12.2011	Bonn						
67	A			14.12.2011	Bonn						
67	A			14.12.2011	Bonn	12.01.2012	Thorsten Krausschek	General testing	06.03.2012	400 V (Ar/Butane 95%)	0.05 nA
67	A			14.12.2011	Bonn						
67	F										
68	A			14.12.2011	Nikhef						
68	A			14.12.2011	Nikhef						
68	B			14.12.2011	Saclay						
68	B			14.12.2011	Saclay						
68	D			14.12.2011	Bonn						





Readout electronics



A successor of MUROS has to be used in next LP-module.

2 candidates:

1) RELAXD system of NIKHEF

very fast (4 chips are readout in parallel)

commercially available

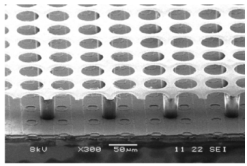
FPGA placed directly on backside of chip carrier

2) Scalable Readout System

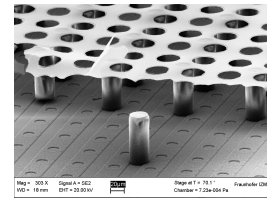
scalable up to large numbers of chips

based on SRS of RD51 → many groups have already the hardware from other applications

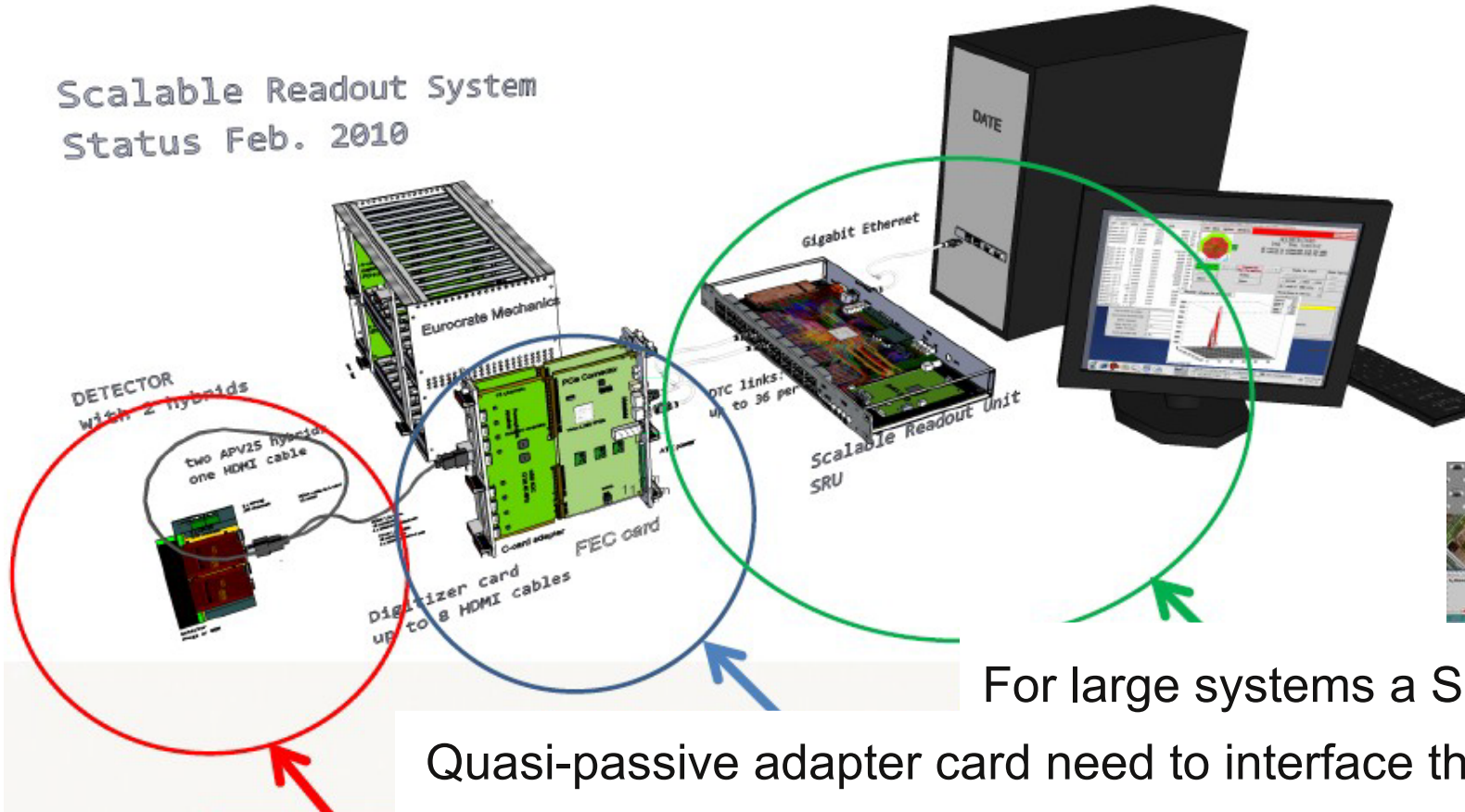
FPGA-code for Timepix readout developed by U Mainz and U Bonn within AIDA - **see presentation of M. Lupberger on Wednesday**



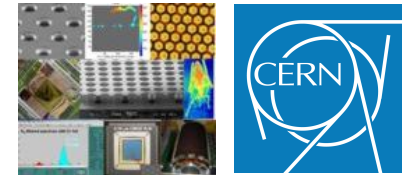
Scalable Readout System



Scalable Readout System
Status Feb. 2010

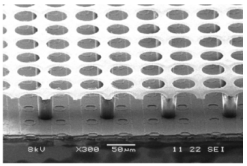


DAQ is a
command line
C++ program
Interfacing to
EUDAQ

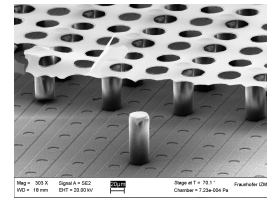


For large systems a SRU is needed
Quasi-passive adapter card need to interface the FEC (FPGA)

Chip carrier with 8 Timepix chips (up to 16 possible, but reduces readout speed)



SRS with Timepix



Currently: VHDCI 68-pin cable

passive A-card

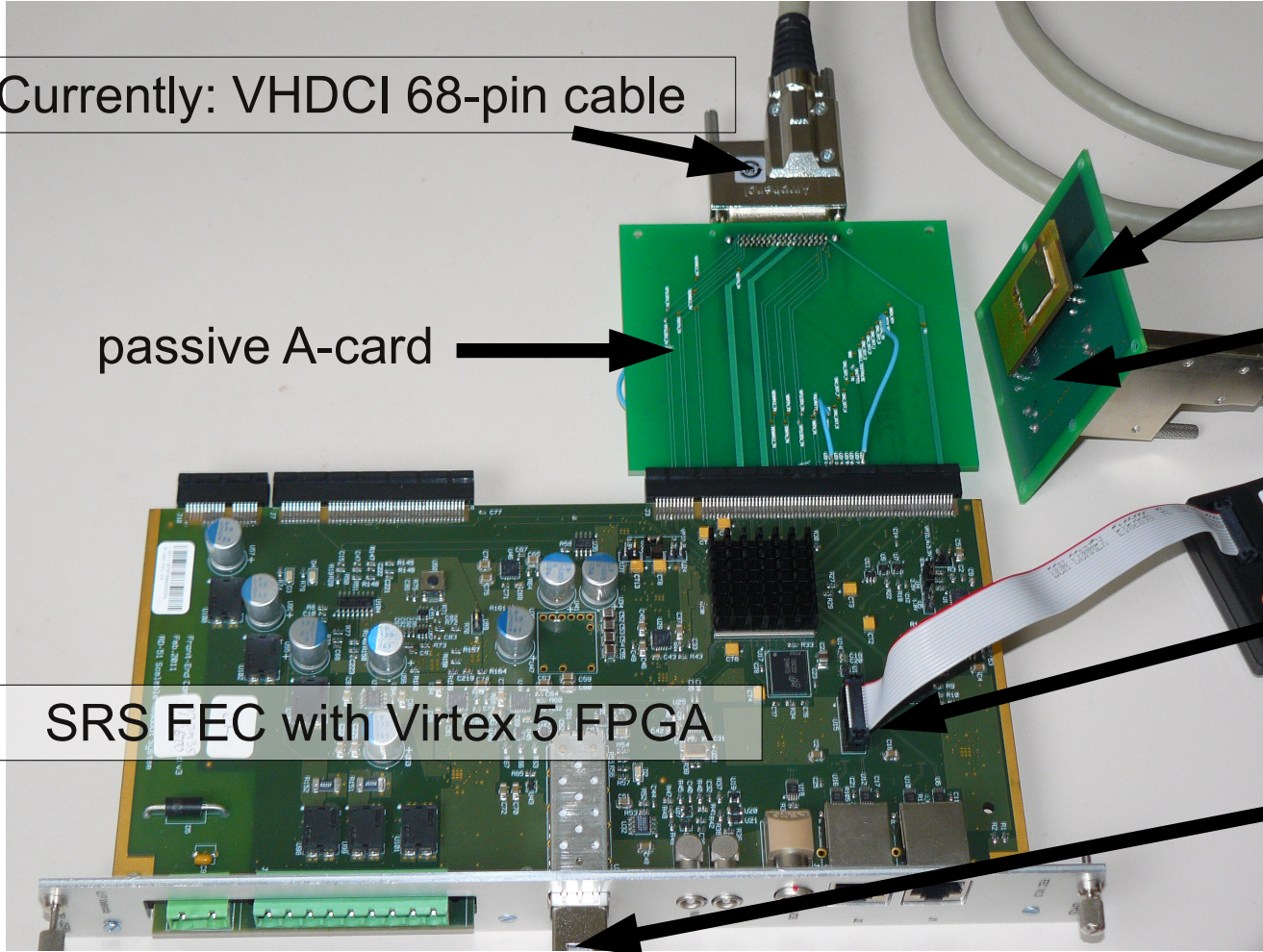
Timepix ASIC
on chip carrier

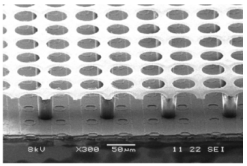
Intermediate
board (layout out
for up to 8 chips)

JTAG connector

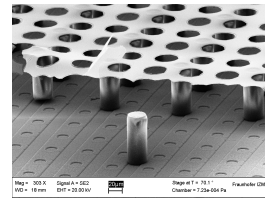
Ethernet
connection to
SRU / PC

SRS FEC with Virtex 5 FPGA





Status



Code has been tested on a separate Xilinx test board.
Readout rates of ~ 50 Hz could be reached with a single chip.
Code is now being tested with SRS
– communication has been established between SRS

Further steps with SRS

Implementation of additional functionality
(equalization, calibration, map handling,)
Hardware modification (different, longer cable, ...)
Development and testing of multi-chip carrier
Integrating EUDAQ



What remains to be done?



- Improve protection layer
- Implement improvements in SRS readout
- Work on layout of module:
 - Where to place chips (small carrier with 8 chips vs. large one)
 - Services
 - Cooling
 - Power distribution
 - HV distribution
- Minimize field distortions in case of InGrids
- Improve 'pixel-branch' of MarlinTPC code (tracking, δ -exclusion..)

Possible roadmap: first a module with DESY-GEMs gas amplification (chips are easier to handle – some issues can be addressed) then one with InGrids, where handling is more delicate



Outlook – even further in the future



Successor Chip Timepix-3

- Design, production and testing
- Build InGrids with Timepix-3

Through Silicon Vias:

- Colleagues at Bonn (N. Wermes / SiLab) are exploring this new Techniques in the context of ATLAS with different chips but in collaboration with IZM
- Once they succeed, we try to copy the process with Timepix

Some more basic R&D:

e.g. new materials (ceramics for pillars, GEMGrids, piggy-back Micromegas, ...)